

Notice of References Cited	Application/Control No. 10/630,716	Applicant(s)/Patent Under Reexamination FUKUYAMA ET AL.	
	Examiner Stephen W. Smoot	Art Unit 2813	Page 1 of 1

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NON-PATENT DOCUMENTS

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	U	Stanley Wolf and Richard N.Tauber, "Silicon Processing for the VLSI Era - Volume 1: Process Technology," Lattice Press, Sunset Beach, California (1986), pp. 182-185.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.